OBLON SPIVAK

McClelland

MAIER

NEUSTADT P.C.

ATTORNEYS AT LAW
STEVEN P. WEIHROUCH
(703) 413-3000

SWEIHROUCH@OBLON.COM

EDWIN D. GARLEPP SENIOR ASSOCIATE

(703) 413-3000 EGARLEPP@OBLON.COM



Docket No: 247562US6YA

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

RE: Application Serial No: 10/766,872

Applicants: Jeffrey T WETZEL et al.

Filing Date: January 30, 2004

For: STRUCTURE COMPRISING AMORPHOUS

CARBON FILM AND METHOD OF FORMING

THEREOF Group Art Unit: 2815

Examiner: WARREN, MATTHEW E.

SIR:

Attached hereto for filing are the following papers:

RESPONSE TO RESTRICTION REQUIREMENT

Our check in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,

MAIER & NEUSTADT, P/C.

Steven P. Weihrouch

Registration No. 32,829

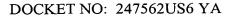
Customer Number

22850

(703) 413-3000 (phone) (703) 413-2220 (fax) Edwin D. Garlepp

Registration No. 45,330

I:\ATTY\EDG\2312 - TOKYO ELECTRON\TEA\TEA 6\247562US\REST CVR 4.05.DOC



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

JEFFREY T. WETZEL ET AL. : EXAMINER: WARREN, MATTHEW E.

SERIAL NO: 10/766,872

FILED: JANUARY 30, 2004 : GROUP ART UNIT: 2815

FOR: STRUCTURE COMPRISING AMORPHOUS CARBON FILM AND METHOD OF

FORMING THEREOF

RESPONSE TO RESTRICTION REQUIREMENT

COMMISSIONER FOR PATENTS ALEXANDRIA, VA 22313-1450

SIR:

In response to the Restriction Requirement dated March 30, 2005, Applicants provisionally elect with traverse Group I, Claims 1-19, drawn to a semiconductor device.

Applicants traverse the Restriction Requirement for the following reason.

MPEP § 803 states:

MPEP § 803

... If the search and examination of an entire application can be made without serious burden, the Examiner must examine it on the merits, even though it includes claims to distinct or independent inventions.

However, the outstanding Restriction Requirement has not established that an undue burden would exist if the Restriction Requirement was not issued and all the claims were examined together. Moreover, the claims of the present invention would appear to be part of an overlapping search area. Accordingly, Applicants respectfully traverse the outstanding Restriction Requirement on the grounds that a search and examination of the entire application would not place a *serious* burden on the Examiner.

Application Serial Number: 10/766,872

Reply to Restriction Requirement dated March 30, 2005

Accordingly, it is respectfully requested that the requirement to elect a single group be withdrawn, and that a full examination on the merits of Claims 1-36 be conducted.

Respectfully submitted,

 $\begin{array}{c} \text{Customer Number} \\ 22850 \end{array}$

Phone: (703) 413-3000 Fax: (703) 413-2220

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Steven P. Weihrouch Registration No. 32,829

Edwin D. Garlepp Registration No. 45,330

SPW:EDG:tdm I:\ATTY\EDG\2312 - TOKYO ELECTRON\TEA\TEA 6\247562US\RESP TO RSTR 4.05.DOC